

JOHNSON ET AL. -- 10/621,464
Client/Matter: 071469-0304543

IN THE ABSTRACT OF THE DISCLOSURE:

Please delete the present Abstract of the Disclosure and replace it with the Abstract of the Disclosure attached hereto.

ABSTRACT OF THE DISCLOSURE

A chuck assembly for supporting a workpiece within a plasma reactor chamber having sidewalls surrounding an interior region capable of supporting a plasma. The assembly includes a chuck base and at least one support arm extending outwardly from the chuck base perimeter to the chamber sidewalls. The chuck assembly includes a workpiece support member which is supported by one or more vertical translation members arranged between and operatively connected to the chuck base and the workpiece support member.